



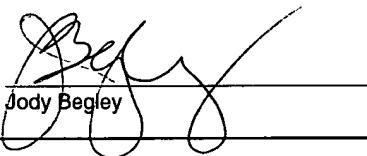
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE  
(Attorney Docket No. MIC-58DV2)

Inventor: Zhang et al. ) Examiner: Mohamedulla  
Serial No. 09/722,400 ) Art Unit: 1756  
Filing Date: November 27, 2000 )  
For: POLYIMIDE AS A MASK IN VAPOR HYDROGEN FLUORIDE  
ETCHING

CERTIFICATE UNDER 37 C.F.R. § 1.8(a)

I hereby certify that this correspondence, and any enclosures referenced herein, is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Assistant Commissioner for Patents, PO Box 1450, Alexandria, VA 22313-1450

on 2/10/, 2004.



Jody Begley

Assistant Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

RESPONSE TO FINAL OFFICE ACTION

In the final office action dated September 17, 2003, the Examiner (1) rejected Claims 34, 38 and 46 under 35 U.S.C. §102(e) as being anticipated by U.S. Patent No. 5,922,623 issued to Tsutsui et al. ("Tsutsui"), (2) rejected Claims 39 and 50 under 35 U.S.C. § 103(a) as being unpatentable over Tsutsui, (3) rejected Claims 9, 11, 27, 28, 29, 31-33, 35, 36, 40, 42, 44, 45, 47 and 48 under § 103(a) as being unpatentable over Tsutsui in view of U.S. Patent No. 5,286,679 issued to Farnworth et al. ("Farnworth"), and (4) rejected Claims 9, 10, 12, 27, 30-33, 35, 37, 40, 43-45, 47 and 49 under § 103(a) as being unpatentable over Tsutsui in view of U.S. Patent No. 5,653,619 issued to Cloud et al. ("Cloud"). Reconsideration and allowance of the application are requested.

02/18/2004 SZEWIDIE1 00000074 080219 09722400

02 FC:1252 420.00 DA